

Please replace the paragraph beginning on page 2, line 26, with the following new paragraph:

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A2  
Another approach is forming a getter at a location along the interior surface of a baseplate or/and faceplate. This is disadvantageous because a getter typically needs a substantial amount of surface area to perform the gas collection function and this approach significantly reduces the active-to-overall area ratio. In addition, the active components of the FED easily become contaminated during the gettering material deposition process and some of the active FED components could become short-circuited.

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Please replace the paragraph beginning on page 6, line 4, with the following new paragraph:

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A3  
Referring now to FIG. 4, therein is shown a schematic cross section of a faceplate 160 of a flat panel display being subject to desorption processing to accelerate outgassing in a vacuum chamber 162 in accordance with a second embodiment of the present invention.

The vacuum chamber 162 is capable of being evacuated by a vacuum pump 164.

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IN THE CLAIMS:

Please amend claims 1-20 as follows. A clean set of claims is presented below. A marked-up copy of the pending claims is appended hereto.

1. (Amended) A method for manufacturing a flat panel display comprising the steps of:
- providing a baseplate and a faceplate;
  - desorption processing the faceplate in a vacuum;
  - merging the baseplate and the faceplate; and
  - sealing the vacuum between the baseplate and the faceplate.
2. (Amended) The method as claimed in claim 1 wherein the step of desorption processing uses a vacuum from  $10^{-7}$  to  $10^{-8}$  torr.
3. (Amended) The method as claimed in claim 2 wherein the step of desorption processing includes the step of scrubbing the faceplate before the step of sealing the vacuum between the baseplate and the faceplate.
4. (Amended) The method as claimed in claim 3 wherein the step of scrubbing the faceplate uses plasma sputtering.
5. (Amended) The method as claimed in claim 4 wherein the step of plasma sputtering uses a low atomic weight gas.
6. (Amended) The method as claimed in claim 4 wherein the step of plasma sputtering uses ions and a faceplate voltage of -10 to -1000 mV.

7. (Amended) The method as claimed in claim 4 wherein the step of plasma sputtering uses electrons and a faceplate voltage of +10 to +1000 mV.

8. (Amended) The method as claimed in claim 4 wherein the step of plasma sputtering applies a faceplate voltage for about 1 to 60 minutes.

B/ 9. (Amended) The method as claimed in claim 1 wherein the step of desorption processing includes a step of pre-aging the faceplate.

10. (Amended) The method as claimed in claim 9 wherein the step of pre-aging the faceplate is performed from 120 to 300 minutes.

11. (Amended) The method as claimed in claim 10 wherein the step of desorption processing includes a step of pre-aging before merge of the baseplate and the faceplate.

12. (Amended) The method as claimed in claim 11 wherein the step of pre-aging uses irradiation with electrons from an electron gun.

13. (Amended) The method as claimed in claim 12 wherein the step of pre-aging uses irradiation with electrons having a current density of 5 to 10 times higher than that of the faceplate during normal operation.

14. (Amended) The method as claimed in claim 10 wherein the step of desorption processing includes a step of pre-aging after merge of the baseplate and the faceplate.

15. (Amended) The method as claimed in claim 14 wherein the step of pre-aging includes application of a voltage of 6 to 9 kV between the baseplate and the faceplate.

16. (Amended) A method for manufacturing a flat panel display comprising the steps of:

providing a baseplate and a faceplate;  
desorption processing the faceplate by scrubbing with plasma sputtering in a vacuum;  
merging the baseplate and the faceplate in the vacuum after the plasma sputtering; and  
sealing the vacuum between the baseplate and the faceplate.

17. (Amended) A method for manufacturing a flat panel display comprising the steps of:

providing a baseplate and a faceplate;  
desorption processing the faceplate by scrubbing with ion plasma sputtering in a vacuum;  
merging the baseplate and the faceplate in the vacuum after the ion plasma sputtering; and  
sealing the vacuum between the baseplate and the faceplate.

18. (Amended) A method for manufacturing a flat panel display comprising the steps of:

- providing a baseplate and a faceplate;
- desorption processing the faceplate by scrubbing with electron plasma sputtering in a vacuum;
- merging the baseplate and the faceplate in the vacuum after the electron plasma sputtering; and
- sealing the vacuum between the baseplate and the faceplate.

19. (Amended) A method for manufacturing a flat panel display comprising the steps of:

- providing a baseplate and a faceplate;
- desorption processing the faceplate by pre-aging using electron irradiation in a vacuum;
- merging the baseplate and the faceplate in the vacuum after the electron irradiation; and
- sealing the vacuum between the baseplate and the faceplate.

20. (Amended) A method for manufacturing a flat panel display comprising the steps of:

- providing a baseplate and a faceplate;
- merging the baseplate and the faceplate;
- evacuating between the baseplate and the faceplate;
- desorption processing the faceplate by pre-aging using electron irradiation during the evacuating between the baseplate and the faceplate to form a vacuum therebetween; and